Special Issue

New Approaches to Micropatterning, Volume II

Message from the Guest Editors

In this Special Issue, we focus on new developments in micropatterning approaches, such as micropatterning within microfluidic devices, multiplexed micropatterning, patterning in three-dimensional structures, as well as new chemistries and materials, and the applications derived from them. We invite original research contributions, short communications, and in-depth reviews from early career and established researchers. The goal of this Special Issue is to capture the state-of-the-art in micropatterning techniques and the wide range of applications that these technologies can be deployed in. We look forward to and welcome your contributions to this Special Issue.

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